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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

🎁 bplicant(s):

MEHRDAD NIKOONAHAD ET AL.

Title:

SCANNING SYSTEM FOR INSPECTION ANOMALIES ON

SURFACES

Application No.:

10/666,120

Filing Date:

September 19, 2003

Examiner:

Unknown

Group Art Unit:

2877

Docket No.:

TNCR.001US4

Conf. No.:

8430

Certificate of Mailing Under 37 CFR 1.8

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on April 7, 2004

Signature

Tracymynox)

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, Applicants call the documents listed on the enclosed Form PTO-1449 to the Examiner's attention in this patent application.

Copies of the documents listed on the accompanying Form PTO-1449 that are not enclosed were previously submitted in Application(s) No. **09/954,287**, from which this Application claims an earlier effective filing date.

Citation of these documents shall not be construed as (1) an admission that the documents are prior art with respect to the invention or inventions claimed in this application, (2) a representation that a search has been made (other than as indicated by any cited document), or

Attorney Docket No.: TNCR.001US4

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(3) an admission that the cited information is, or is considered to be, material to patentability as defined in § 1.56(b).

This information disclosure statement is submitted under 37 C.F.R. § 1.97(b) and consequently no fee should be required. The Commissioner is authorized, however, to charge any fee that may be required, or to credit any overpayment, against Deposit Account No. 502664. This form is being submitted in duplicate.

Respectfully submitted,

James S. Hsue

Reg. No. 29,545

4-7-04

Date

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		Commerce, Patent		Atty. Docket No.			Application No.		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				TNCR.001US4			10/666,120		
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Examiner			Date Considere						

* US PTO did not receive these documents